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Docket No. EATNP151US

02-IMP-076

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re **PATENT** application of:

Applicant: Kevin W. Wenzel, et al.

Application No.: 10/632,234

For: METHOD AND SYSTEM FOR ION BEAM CONTAINMENT USING  
PHOTOELECTRONS IN AN ION BEAM GUIDE

Filing Date: July 31, 2003

Examiner: Quash, Anthony G.

Art Unit: 2881

**REPLY TO OFFICE ACTION DATED JUNE 10, 2004**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Favorable reconsideration of the above-identified application is respectfully  
requested in view of the following amendment and remarks.